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APPLICATION NO.	FI	LING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.	
10/718,102 11/19/2003			Kramadhati V. Ravi	42P17822	9900	
8791	7590	06/17/2005		EXAMINER		
BLAKELY 12400 WILS	-	OFF TAYLOR &	PHAM, THANHHA S			
SEVENTH I		OLEVARD	ART UNIT	PAPER NUMBER		
LOS ANGE	LES, CA	90025-1030	2813	2813		

DATE MAILED: 06/17/2005

Please find below and/or attached an Office communication concerning this application or proceeding.

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		10/718,10	2	RAVI, KRAMADHATI V.			
	Office Action Summary	Examiner		Art Unit			
		Thanhha F		2813			
Period fo	The MAILING DATE of this communication or Reply	on appears on the	cover sheet with the c	orrespondence address			
A SHORTENED STATUTORY PERIOD FOR REPLY IS SET TO EXPIRE 1 MONTH(S) FROM THE MAILING DATE OF THIS COMMUNICATION. - Extensions of time may be available under the provisions of 37 CFR 1.136(a). In no event, however, may a reply be timely filed after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a reply within the statutory minimum of thirty (30) days will be considered timely. - If NO period for reply is specified above, the maximum statutory period will apply and will expire SIX (6) MONTHS from the mailing date of this communication. - Failure to reply within the set or extended period for reply will, by statute, cause the application to become ABANDONED (35 U.S.C. § 133). Any reply received by the Office later than three months after the mailing date of this communication, even if timely filed, may reduce any earned patent term adjustment. See 37 CFR 1.704(b).							
Status				•			
1)⊠	Responsive to communication(s) filed on	Responsive to communication(s) filed on <u>01 February 2005</u> .					
,	· · · · · · · · · · · · · · · · · · ·	This action is n					
3)	Since this application is in condition for a						
	closed in accordance with the practice ur	nder <i>Ex parte Qu</i>	ayle, 1935 C.D. 11, 45	53 O.G. 213.			
Disposit	ion of Claims						
4) 🖂	Claim(s) 1-21 is/are pending in the applic	cation.					
-	4a) Of the above claim(s) is/are withdrawn from consideration.						
	5) Claim(s) is/are allowed.						
	Claim(s) is/are rejected.						
-	Claim(s) is/are objected to. Claim(s) <u>1-21</u> are subject to restriction ar	nd/or election rec	uirement				
0)(2)		114,01 010011011100	,				
Applicat	ion Papers						
	9) The specification is objected to by the Examiner.						
10)	10) The drawing(s) filed on is/are: a) accepted or b) objected to by the Examiner.						
	Applicant may not request that any objection to the drawing(s) be held in abeyance. See 37 CFR 1.85(a).						
11)	Replacement drawing sheet(s) including the correction is required if the drawing(s) is objected to. See 37 CFR 1.121(d). 11) The oath or declaration is objected to by the Examiner. Note the attached Office Action or form PTO-152.						
Priority under 35 U.S.C. § 119							
12) Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f). a) All b) Some * c) None of:							
1. Certified copies of the priority documents have been received.							
2. Certified copies of the priority documents have been received in Application No							
3. Copies of the certified copies of the priority documents have been received in this National Stage application from the International Bureau (PCT Rule 17.2(a)).							
* (* See the attached detailed Office action for a list of the certified copies not received.						
			•	,			
Attachmer	nt(s)						
1) Notice of References Cited (PTO-892) 4) Interview Summary (PTO-413)							
2) D Notic	ce of Draftsperson's Patent Drawing Review (PTO-9		Paper No(s)/Mail D Notice of Informal F				
,	3) Information Disclosure Statement(s) (PTO-1449 or PTO/SB/08) Paper No(s)/Mail Date 5) Notice of Informal Patent Application (PTO-152) 6) Other:						

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DETAILED ACTION

Election/Restrictions

- 1. Restriction to one of the following inventions is required under 35 U.S.C. 121:
 - Claims 1-8, classified in class a method comprising testing a semiconductor tool using the wafer, classified in class 438, subclass 14.
 - II. Claims 9-13, drawn to a method comprising removing surface contaminant, classified in class 438, subclass 689.
 - III. Claims 14-21, drawn to an apparatus, classified in class 118, subclass712.

The inventions are distinct, each from the other because of the following reasons:

2. Inventions I and III are related as process and apparatus for its practice. The inventions are distinct if it can be shown that either: (1) the process as claimed can be practiced by another materially different apparatus or by hand, or (2) the apparatus as claimed can be used to practice another and materially different process. (MPEP § 806.05(e)). In this case, the process invention I can be practiced by another materially different apparatus, for example, providing a coating over a wafer wherein the coating comprises at least one characteristic of a single crystal can practiced in a conventional coating apparatus without a semiconductor tool testing configuration. In addition, the apparatus invention III can be used to practice another and materially different process, for example, testing a silicon wafer including a coating wherein the coating does not comprise at least a characteristic of a single crystal.

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Inventions II and III are related as process and apparatus for its practice. The inventions are distinct if it can be shown that either: (1) the process as claimed can be practiced by another materially different apparatus or by hand, or (2) the apparatus as claimed can be used to practice another and materially different process. (MPEP § 806.05(e)). In this case, the process invention II can be practiced by another materially different apparatus, for example, removing surface contaminants from the wafer can be practiced a conventional etching apparatus without a semiconductor tool testing configuration. In addition, the apparatus invention III can be used to practice another and materially different process, for example, testing a silicon wafer including a coating wherein the coating does not comprise at least a characteristic of a single crystal.

- 3. Inventions I and II are unrelated. Inventions are unrelated if it can be shown that they are not disclosed as capable of use together and they have different modes of operation, different functions, or different effects (MPEP § 806.04, MPEP § 808.01). In the instant case the different inventions, the method inventions I & II have different modes of operation, different functions, or different effects. For example, the method invention I is drawn to a method comprising testing a semiconductor tool using the wafer while the method invention II is drawn to a method comprising removing surface contaminants from the wafer.
- 4. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art as shown by their different classification, restriction for examination purposes as indicated is proper.

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5. Because these inventions are distinct for the reasons given above and the search required for Group I is not required for Group II or III, restriction for examination purposes as indicated is proper.

- 6. Because these inventions are distinct for the reasons given above and have acquired a separate status in the art because of their recognized divergent subject matter, restriction for examination purposes as indicated is proper.
- Applicant is advised that the reply to this requirement to be complete must include an election of the invention to be examined even though the requirement be traversed (37 CFR 1.143).
- 8. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Thanhha Pham whose telephone number is (571) 272-1696. The examiner can normally be reached on Monday and Thursday 9:00AM 9:30PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead can be reached on (571) 272-1702. The fax phone number for the organization where this application or proceeding is assigned is 703-872-9306.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free).

Thanhha Pham Patent Examiner

Patent Examining Group 2800